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PATENT APPLICATION
RE Randa A

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Atsushi ITO, Yasuji HIRAMATSU,
Yasutaka ITO, and Masakazu FURUKAWA

Appln. No.: (Not Yet Designated)

Group Art Unit: Unknown

Filed: October 24, 2000

Examiner: Unknown

For: WAFER PROBER

October 24, 2000

PRELIMINARY AMENDMENT

Assistant Commissioner for Patents
Washington, D. C. 20231

Sir:

Prior to examination of the above-identified application,
please amend the application as follows:

IN THE CLAIMS:

In claim 3, at line 1, delete "or 2".

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5. (twice amended) A wafer prober according to claim 1
[which comprises a ceramic substrate and a conductor layer formed
on the surface thereof], wherein said ceramic substrate is
equipped with a Peltier⁵ device.

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6. (twice amended) A wafer prober according to claim 1
[which comprises a ceramic substrate and a conductor layer formed
on the surface thereof], wherein on said ceramic substrate,
channels are⁶ formed.

to do what

also known as thermoelectric
cooling device